

What is claimed is:

1. A light-emitting diode comprising a light-emitting diode chip  
mounted on a surface of a printed substrate, the light-emitting diode  
5 chip including:

a substrate;

a semiconductor layer laminated on the substrate and formed of  
an N-type semiconductor layer and a P-type semiconductor layer,  
wherein its PN junction surface is perpendicular to the surface of the  
10 printed substrate and a portion in the vicinity of the PN junction  
surface is rendered to be a light-emitting portion;

a pair of electrodes for applying voltage to the semiconductor  
layer; and

a light reflecting layer for reflecting light emitted from the  
15 light-emitting portion,

wherein the light reflecting layer is formed on a front surface or a  
back surface of the light-emitting diode chip or in the light-emitting  
diode chip and is approximately parallel to the PN junction surface.

20 2. A light-emitting diode claimed in Claim 1, wherein the substrate  
is made of a transparent substrate and the light reflecting layer is  
formed on the front surface or back surface of the transparent substrate  
or on the surface of the semiconductor layer.

3. A light-emitting diode claimed in Claim 2, wherein the light reflecting layer comprises a DBR diffraction grating structure formed on the surface of the transparent substrate.

*Due AX2* 5 4. A light-emitting diode claimed in Claim 1 or 2, wherein the light reflecting layer is formed of a metal thin film.

10 5. A light-emitting diode claimed in Claim 4, wherein the metal thin film is formed directly or via a dielectric thin film on the back surface of the transparent substrate.

*Due AX3* 6. A light-emitting diode claimed in Claim 4 or 5, wherein the metal thin film is formed of an Ni vapor-deposition film.

*Due AX4* 15 7. A light-emitting diode claimed in Claim 5, wherein the dielectric thin film is formed of an SiO<sub>2</sub> film or an Al<sub>2</sub>O<sub>3</sub> film, and the metal thin film is formed of an AuBe vapor-deposition film or an Au vapor-deposition film.

20 8. A light-emitting diode claimed in any one of Claims 1 to 7, wherein the Ni vapor-deposition film has a thickness of 100 nm or more.

9. A light-emitting diode claimed in Claim 7, wherein the SiO<sub>2</sub> film

or the  $\text{Al}_2\text{O}_3$  film has a thickness of approximately 3 to 60 nm, and the AuBe vapor-deposition film or the Au vapor-deposition film has a thickness of approximately 3 to 60 nm

5 10. A light-emitting diode claimed in any one of Claims 1 to 9,  
wherein the substrate is formed of a transparent substrate transparent  
to color emitted by the light-emitting diode chip.

11. A method for manufacturing a light-emitting diode comprising  
10 mounting, on a surface of a printed substrate, a light-emitting diode  
chip having a substrate, a semiconductor layer which is laminated on a  
surface of the substrate, is formed of an N-type semiconductor layer  
and a P-type semiconductor layer and has a light-emitting portion in  
the vicinity of a PN junction surface between the N-type and P-type  
15 semiconductor layers, a pair of electrodes for applying voltage to the  
semiconductor layer, and a light reflection layer reflecting light emitted  
from the light-emitting portion ,thereby obtaining the light-emitting  
diode, the method comprising, for mounting the light-emitting diode  
chip on the printed substrate,  
20 the step of forming beforehand the light reflecting layer on a  
front surface or a back surface of the substrate of the light-emitting  
diode chip or in the light-emitting diode chip in such a manner that the  
light reflecting layer is approximately parallel to the PN junction surface,  
and

the step of fixing the obtained light-emitting diode chip on the printed substrate so that the PN junction surface is perpendicular to the surface of the spring substrate and electrically connecting the pair of electrodes of the light-emitting diode chip to the printed substrate.

add  
AG